AEC/APC Symposium Asia 2019

Call for Papers!

Creating new value with digital twin based on data science

Wednesday, November 13, 2019

National Center of Sciences Building (Gakujutsu Sogo Center)
Tokyo, Japan

https://www.semiconportal.com/AECAPC/

AEC/APC symposium calls its annual conference in North America, Europe, and Asia. The suppliers of the device, the equipment, the material, the software, the sensor, and the metrology shall meet, and discuss the more intelligent and the higher productive manufacturing system in the conferences. The conference is held in Taiwan and Japan every other year. AEC/APC is called the core of the scientific manufacturing technology. The technology has created the extensive progress of the productivity improvement and the yield improvement in the semiconductor manufacturing area. The technology discussed in the conferences has been applied and used in the process technology of LCD, PV and Battery.

In Japan, the 7th conference is called in this year event since the 1st conference of 2007. Since 2007, the conference has discussed the scientific manufacturing technology using the data which can monitor the manufacturing equipment and the process conditions. This year, the symposium puts the subtitle “Value creation with digital twin based on data science”.

The symposium is a very good chance among the technical authorities from Japan and from out of Japan to share their knowledge and technologies in AEC/APC area. The symposium can also be a very good chance for the professionals of the process control industry such as semiconductor to meet and discuss.

Today, this area already forms the core part of the manufacturing engineering technology. The role of this symposium is very important, since people can share the information and the directions of the process control improvement, the equipment productivity improvement, and the material source reduction for the future.

* AEC: Advanced Equipment Control
* APC: Advanced Process Control

Online Abstract Submission Procedure:

- Prospective authors are requested to submit the abstract through web browser, consisting of exactly two pages of A4-paper size.
- The first page consists of the text (max of 1,000 words) and the second page consists of figures, supporting data, charts, photos and drawings.
- Only PDF files are compatible.
- The abstract must be written in English, using the online abstract submission form (MS word).

Information, templates, and other details are available on the website:
https://www.semiconportal.com/AECAPC/cfp_e.html

Abstract submission start
Friday, May 31st, 2019

Abstract submission due
Tuesday, July 9th, 2019

Notification of acceptance
Friday, August 30th, 2019

Presentation materials due
*only for accepted authors
Friday, October 18th, 2019

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Area of Interests

**Equipment and Process Control**
FDC (Fault detection and classification)
SPC (Statistical process control)
Run-to-run Control
RMS (Recipe Management System)

**Model-based Process Control**
Physical and chemical process models
Soft sensor
Virtual metrology

**Tool Data Acquisition and Analysis**
Data collection
Sensor development
Failure and Yield Analysis
Statistical approaches
Bigdata Analysis
AI, Machine Learning
Enhanced equipment quality Assurance

**APC Strategy**
Future Needs and opportunities
SDGs (Sustainable Development Goals)
Standard

**Region Expansion**
Back-end process
MEMS (MEMS)
Display device
Solar panel
Battery

Call for Sponsors and Exhibitors!
AEC/APC Symposium Asia provides the opportunity to get insight in the latest status of AEC/APC and to network with your partners and potential customers.
For detail, please visit [https://www.semiconportal.com/AECAPC/](https://www.semiconportal.com/AECAPC/)

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